Zirconium Borohydride as a Zirconium **Boride** Precursor

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Synthesis of zirconium boride, ZrB_2 , from zirconium borohydride, $Zr(BH_4)_4$, has been explored by a variety of methods, including chemical vapor deposition (CVD) in a hot tube, laser CVD with both continuous-wave (cw) and pulsed lasers, and cw-laser synthesis of fine powders. In all cases, ZrB_2 was the only crystalline product identified. Products made at high temperature contained excess boron, while those made at low temperature were boron-deficient.

METAL borides tend to be hard, refrac-tory materials with substantial chemical inertness. The materials form a wide range of compositions, from M₅B to MB₁₂,^{1,2} with quite varied structures.^{2,3} Syntheses of bulk borides have been accomplished by direct combination of the elements, reduction of metal oxides with B or B₄C, and coreduction of mixed metal and boron oxides with carbon. Such preparations have typically been conducted at >1000°C.¹

There are several reports in the literature on the preparation of thin coatings of metal diborides, MB₂, through chemical vapor deposition (CVD) by H_2 reduction of mixed BCl₃ and MCl_x gases.⁴⁻¹⁰ Group IV (Ti, Zr, and Hf) diboride films were initially made at 1400°C.¹⁰ Subsequent depositions of TiB₂ on graphite have been accomplished at temperatures as low as 800°C.8,9 and (Ti,Zr)B₂ solid solutions were reported to form on graphite at 900° to 1400°C from mixtures of TiCl₄, ZrCl₄, BCl₃, and H₂.⁶ However, Randich found that coatings formed on graphite at 900°C from such mixtures contained no zirconium, while at 1100°C the Zr/Ti ratio in the coating was only one-tenth of that in the gas.⁴ The result is consistent with the relative ease of reduction of titanium(IV) versus zirconium(IV).11

Chemical vapor deposition of metal boride coatings from the chlorides limits the choice of substrate. Pierson and Randich pointed out that preparing good CVD coatings of TiB₂ from the chlorides requires that the substrate withstand both the high deposition temperature employed and the HCl byproduct.5,6

The highly volatile group IV borohydrides — $Ti(BH_4)_3$, $Zr(BH_4)_4$, and

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Hf(BH₄)₄-are attractive molecular precursors to the borides. When first prepared by Hoekstra and Katz, they were reported to decompose at very slow (Zr and Hf) to moderate (Ti) rates to nonvolatile solids of indefinite composition.¹² Although pyrolysis of the Th(BH₄)₄ analogue was reported to yield ThB_{3.83},¹² pyrolysis of $Zr(BH_4)_4$ has been claimed to give "zirconium in a mixture of zirconium boride" as a coating on graphite.¹³ There is also a recent patent reporting use of Zr(BH₄)₄ to deposit boroncontaining material as a "consumable poison" on uranium dioxide nuclear fuel. A recent paper by Gallagher et al. on preparation of the group IV diborides from the borohydrides¹⁵ prompts us to report our experiments with Zr(BH₄)₄. We have conducted Zr(BH₄)₄ pyrolysis by a variety of methods at different temperatures and find that it can be decomposed either to a coating or to a high-surface-area powder.

EXPERIMENTAL PROCEDURE

Zirconium tetrachloride, LiBH₄, and LiBD₄ were purchased[†] and used as received. All reactions were conducted under dry nitrogen in a glove box^{*} or in Schlenktype glassware.¹⁶ Synthesis of Zr(BH₄)₄ has been reported by several methods, including reaction of NaZrF5 with liquid $Al(BH_4)_3$,¹² reaction of ZrCl₄ and LiBH₄ in ether,¹⁷ and reaction of ZrCl₄ and LiBH₄ by "intensive grinding" of the dry solids in a vacuum ball mill at 100°C.¹⁸ Since the purchased materials were fine powders, good yields were obtained in the laboratory by magnetic stirring of the dry solids in a flask above the melting point $(29^{\circ}C^{12})$ of the product. After a fairly long induction time, the liquid Zr(BH₄)₄ produced seemed to act as a flux for further reaction. The product was separated from residues by vacuum sublimation into a chilled flask. The deuterated analogue, Zr(BD₄)₄, was similarly produced using LiBD₄ and ZrCl₄ reactants. Caution: Zr(BH₄)₄ and residues from its synthesis react violently with air or protic solvents.

Conventional CVD experiments employed iron-foil substrates in a 25-mmdiameter glass tube in a small tube furnace. The Zr(BH₄)₄ was held at 0°C, where its reported vapor pressure is 240 Pa (1.8 torr^{12}) ,

and continuously pumped past the substrates with a roughing pump capable of an ultimate pressure of 10 Pa. The (unmeasured) pressure in this dynamic system was estimated to be 100 Pa. This vapor was admitted to the hot-walled reaction tube via a room-temperature, 8-mm tube terminating near the iron substrates. Experiments in the same reactor, but using atmosphericpressure argon as a carrier for Zr(BH₄)₄ (22°C source, 1.6 kPa, 1.6% Zr(BH₄)₄), produced fine powders in addition to coatings. While fine powders are themselves of interest, conditions that yield powders are unsuitable for coating deposition.

Laser CVD was attempted by several methods. In all cases, the irradiation cells contained only $Zr(BH_4)_4$, with its pressure controlled over a range of 240 Pa to 2 kPa by maintaining the source between 0° and 25°C. With CO₂ infrared lasers, operating at 10.6 μ m, no coatings were produced on reflective metallic substrates (continuous-wave (cw): 20 W; pulsed: 2 J/pulse, 110-ns full width at half-maximum (FWHM), 2 J/cm^2), but coatings could be formed on absorbing quartz surfaces (cw: 4 W). Deposition on metallic substrates was achieved with a pulsed Nd:YAG near-infrared laser operating at 1.06 µm (200 mJ/pulse, 25-ns FWHM, 6-Hz repetition rate, 5 J/cm^2). Absorption of laser radiation by Zr(BH₄)₄ is small at both 10.6 and 1.06 μ m, and all reactions are due to laser-induced surface heating.

Powder synthesis was attempted using laser-pyrolysis methods that have been described previously.^{19,20} Zirconium borohydride has no strong absorptions in the spectral region accessible with CO₂ lasers, so pyrolysis experiments used either $Zr(BH_4)_4$ with SF_6 sensitizer and the 10 P(20) laser line at 944 cm⁻¹, or the deuterated analogue Zr(BD₄)₄ with no sensitizer and the 10 P(22) laser line at 942 cm⁻¹. Laser power was 20 W in both cases.

RESULTS

Conventional CVD

Conventional CVD on iron substrates was examined at three temperatures. At 182°C, no deposition occurred. At 265° and 398°C, however, the pyrolysis appeared to go to completion because coatings on the hot-walled reaction tube were localized near the reactant inlet. The results of a series of Auger electron spectroscopic analyses, made while sputtering away the coating produced at 265°C, are shown in Fig. 1.[§] It shows that a 2-min deposition produced a coating \approx 150 nm thick, with a 3- to 5-nm oxide surface layer. The boride layer's composition was ZrB_{1.6}. This presumably corresponds to the previous report of zirconium-zirconium boride mixtures formed by pyrolysis of the borohydride.¹³ Corresponding analysis of a coating produced on iron at 398°C revealed at 450-nm boride layer with the composition $ZrB_{3,1}$, and a 1- to 3-nm oxide surface layer. Elemental analysis[¶] of flakes scraped from the

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Fig. 1. Auger sputtering depth profile of a zirconium boride coating on iron produced at 265°C.

reactor wall in the same run gave the composition ZrB_{3.3}, in substantial agreement with the Auger result. X-ray diffraction on the ZrB_{3.3} flakes indicated that ZrB₂ was the only crystalline phase present. Diffraction peaks were very broad (3° to 5°). These sharpened to 1° after vacuum annealing at 900°C for 16 h, but no new phases --- such as ZrB_{12} or B — were observed that would account for the excess boron.

The different coating compositions obtained at 265° and 398°C imply an intermediate, optimum temperature for forming stoichiometric ZrB₂. Since the excess boron in Zr(BH₄)₄ must be transported away from the coated surface as volatile boranes, which themselves decompose by hydrogen loss at relatively low temperature,²¹ coating composition may be affected by conditions such as gas-flow velocities and pressure of added hydrogen as well as substrate temperature. The following section shows that transient heating also permits removal of the borane byproducts.

Laser CVD

Laser CVD was attempted under conditions intended to produce coatings by localized heating of substrates. Laser CVD on metal substrates with a 20-W cw CO₂ laser was unsuccessful because of the high reflectivity of the substrates. Deposition on absorbing quartz substrates was achieved with only 4 W of incident power. The coatings were smooth when very thin but spalled off as deposition continued. Thin coatings were adherent, whereas thicker ones could be wiped away easily. It was also noted that reducing the Zr(BH₄)₄ pressure from 1500 to 400 Pa substantially increased coating adherence and resistance to dissolution by aqua regia.

Laser-CVD coatings on iron substrates were obtained with 1.06-µm radiation, where iron is less reflective than at 10.6 μ m. A near-infrared laser CVD (10 min of irradiation, 3600 pulses) was compared with two conventional CVD experiments (398°C for 3 min, 265°C for 11 min). Auger analysis of the pulsed-laser CVD coating showed that it was nearly stoichiometric, with a composition of ZrB_{2.1}. Measured at the depths where sputtering exposed equal amounts of coating and substrate, the laser-produced coating was much thinner (10 nm) than the conventional coatings (160 and 510 nm for the 398° and 265°C coatings, respectively.) These thicknesses and deposition times yield calculated deposition rates of 1 nm/s for the laser-CVD coating, 9 nm/s for the 398°C conventional coating, and 8 nm/s for the 265°C conventional coating. However, the laser pulse width was only 25 ns, so the exposure time in the laser-CVD experiment was only 90 μ s for 3600 pulses. This gives a deposition rate of 110000 nm/s during exposure of the substrate to laser radiation. The high deposition rate with laser CVD suggests high transient surface temperatures, and the stoichiometric ZrB₂ composition indicates that borane byproducts are able to diffuse away from the reaction zone between pulses, thereby avoiding incorporation of excess boron into the coating.

Powder Synthesis

The laser-driven powder-synthesis experiments are more aptly described as informative rather than successful. Zirconium borohydride has only one very weak absorption band, centered at 1033 cm^{-1} , in the spectral range accessible with CO₂ lasers. No solid product was obtained by irradiation at 1045 cm^{-1} on the wing of this band. Upon deuteration, a stronger absorption band that occurs at 1222 cm⁻¹ in $Zr(BH_4)_4$ shifts down to 917 cm⁻¹ (shoulder at 935 cm⁻¹) in Zr(BD₄)₄, and powder was obtained by irradiation at 933 cm⁻¹. These powders were black and free-flowing, with very broad X-ray diffraction peaks for ZrB₂, but their analytical compositions ranged from ZrB_{3.3} to ZrB_{3.7}. Brunauer-Emmett-Teller surface areas were 40 to 125 m²/g for different runs. The powders were remarkably air-sensitive. Although bulk ZrB2 is quite oxidation-resistant,^{22,23} with potential short-term use to 1500°C,²⁴⁻²⁶ laser-synthesized powders exposed to air immediately became red hot and changed to white oxides. Air sensitivity is undoubtedly due to the high surface area.

Pyrolysis of Zr(BH₄)₄/SF₆ mixtures was attempted because SF₆ absorbs strongly at 944 cm⁻¹ and is often used as a sensitizer in laser-chemistry experiments.²⁷ In this case, it was not a sensitizer but a reactant. X-ray diffraction clearly showed that both ZrB_2 and ZrF_4 were present in the product, and ZrS₂ lines were tentatively identified as well. Elemental analysis of the powder gave the empirical formula $ZrS_{0.6}F_{1.3}B_{1.7}$.

DISCUSSION

This work was undertaken to determine whether Zr(BH₄)₄ had any potential as a ZrB₂ precursor. The results show that it does. Laser synthesis of the diboride powder from the borohydride, however, is less attractive than other powder-synthesis methods recently reported. These include conventional pyrolysis of group IV boro-

The availability of borohydride precursors for other metals is, unfortunately, rather limited. Titanium, zirconium, and hafnium are the only transition metals reported to form volatile borohydrides that can be isolated without additional ligands.² Volatile nontransition-metal borohydrides are few, including those of beryllium, aluminum, thorium, and uranium.¹² The laser-CVD work with $Zr(BH_4)_4$ is highly predictive of the behavior of Hf(BH₄)₄, because "the chemistries of zirconium and hafnium are more nearly identical than for any other two cogeneric elements."³⁰ The Zr(BH₄)₄ work is less predictive of Ti(BH₄)₃ behavior, but laser CVD of TiB₂ coatings from Ti(BH₄)₃ should also be possible.

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REFERENCES

¹N. N. Greenwood, "Metal Borides," Q. Rev.

¹N. N. Greenwood, "Metal Borides," *Q. Rev. Chem. Soc.*, **20**, 441–64 (1966). ²N. N. Greenwood, "Boron"; pp. 665–991 in Comprehensive Inorganic Chemistry, Vol. 1. Edited by J. C. Bailar, Jr. Pergamon, Oxford, 1973. ³A. F. Wells; pp. 1049–57 in Structural Inorganic Chemistry. Clarendon Press, Oxford, 1984.

Chemistry. Clarendon Press, Oxford, 1984. ⁴E. Randich, "Chemical Vapor Deposited Borides of the Form (Titanium, Zirconium) Diboride and (Tan-talum, Titanium) Diboride," *Thin Solid Films*, **63**, 309–13 (1979). ⁵H. O. Pierson and E. Randich, "Titanium Di-boride Coatings and Their Interaction with the Sub-strates," *Thin Solid Films*, **54**, 119–28 (1978). ⁶H. O. Pierson and E. Randich, "The Coating of Metals with Titanium Diboride by Chemical Vapor De-position," *Proc. Electrochem. Soc.*, **77-5**, 304–17 (1977). ⁷H. O. Pierson, E. Randich, and D. M. Mattox, "The Chemical Vapor Deposition of Titanium Diboride on Graphite," *J. Less-Common Met.*, **67**, 381–88 (1979).

(1979). ⁸T. Takahashi and H. Kamiya, "Chemical Vapor Deposition of the System Titanium-Zirconium-Boron," *High Temp.*—*High Pressures*, **9**, 437-43

Boron," High Temp. — High Treasmont, J., 11 (1977).
"T. Takahashi and H. Kamiya, "Chemical Vapor Deposition of Titanium Diboride," J. Cryst. Growth, 26, 203-09 (1974).
¹⁰J. J. Gebhardt and R. F. Cree, "Vapor-Deposited Borides of Group IVA Metals," J. Am. Ceram. Soc., 48 [5] 262-67 (1964).
¹¹F. A. Cotton and G. Wilkinson; pp. 701 and 829 in Advanced Inorganic Chemistry, 4th ed. Wiley, New York. 1980.

in Advanced Inorganic Chemistry, 4th ed. Wiley, New York, 1980. ¹²H. R. Hoekstra and J. J. Katz, "The Preparation and Properties of the Group IV-B Metal Borohydrides," J. Am. Chem. Soc., 71, 2488–92 (1949). ¹³G. A. Domrachev, V. V. Mel'nikov, G. B. Ka-sarinov, G. A. Skorik, and K. K. Fukin, "Deposition of Inorganic Coatings from the Vapor Phase," British Pat. No. 1 306 784 (1973). ¹⁴J. D. Feichtner and J. T. Veligdan, "Coating a Substrate by Thermal Decomposition of a Metallic Compound," French Pat. No. 2 567 542 (1986). ¹⁵M. K. Gallagher, W. E. Rhine, and H. K. Bowen, "Low-Temperature Route to High-Purity Ti-

Bowen, "Low-Temperature Route to High-Purity Ti-tanium, Zirconium, and Hafnium Powders and Films"; presented at the 89th Annual Meeting of the American Ceramic Society, Pittsburgh, PA, April 27, 1987 (Paper

No. 63–B–87). ¹⁶D. F. Shriver and M. A. Drezdzon; pp. 30–41 in The Manipulation of Air-Sensitive Compounds, 2nd ed. Wiley, New York, 1986. ¹⁷B. D. James and B. E. Smith, "Convenient,

High-Yield Syntheses of Bis(tetrahydroborato)-bis(cyclopentadienyl)zirconium(IV) and Tetrakis-(tetrahydroborato)zirconium(IV)," Synth. React. Inorg. Met. Org. Chem., 4, 461-65 (1974).
¹⁸V. V. Volkov, K. G. Myakishev, and S. I. Yugov, "Synthesis of Zirconium Tetrahydroborate by the Reaction of Zirconium Chloride with Lithium Tet-rahydroborate," J. Appl. Chem. USSR (Eng. Transl.), 48, 2184 (1975).
¹⁹G. W. Rice, "Laser Synthesis of Si/C/N Pow-ders from 1,1,1,3,3,3-Hexamethyldisilazane," J. Am. Ceram. Soc., 69 [8] C-183-C-185 (1986).
²⁰G. W. Rice, "Laser-Driven Pyrolysis: Syn-thesis of TiO₂ from Titanium Isopropoxide," J. Am. Ceram. Soc., 70 [5] C-117-C-120 (1987).
²¹F. A. Cotton and G. Wilkinson; pp. 289-305 in Advanced Inorganic Chemistry, 4th ed. Wiley, New York, 1980.

²²A. Lebugle and G. Montel, "Different Processes of Zirconium Diboride Oxidation," C.R. Acad. Sci.

of Zirconium Diboride Oxidation," C.R. Acad. Sci. Ser. C, 274, 1512-15 (1972). ²³A. Lebugle and G. Montel, "Comparative Study of the Oxidation of Zirconium, Hafnium, and Titanium Diborides," Rev. Int. Hautes Temp. Refract., 11, 231-44 (1974). ²⁴H. C. Graham, H. H. Davis, I. A. Kvernes, and W. C. Tripp, "Microstructural Features of Oxide Scales Formed on Zirconium Diboride Materials," Mater. Sci. Res., 5, 35-48 (1971).

Formed on Zirconium Diboride Materials," *Mater. Sci. Res.*, 5, 35–48 (1971). ²⁵W.C. Tripp and H.C. Graham, "Thermogravi-metric Study of the Oxidation of Zirconium Diboride in the Temperature Range of 800° to 1500°C," *J. Electrochem. Soc.*, **118**, 1195–99 (1971). ²⁶W.C. Tripp, H. H. Davis, and H. C. Graham, "Effect of an SiC Addition on the Oxidation of ZrB₂," *Am. Carem. Soc.*, **118**, 1612, 16 (1072).

Am. Ceram. Soc. Bull., 52 [8] 612-16 (1973).

²⁷W.C. Danen and J.C. Jang, "Multiphoton Infrared Excitation and Reaction of Organic Com-pounds"; pp: 86–92 in Laser-Induced Chemical Proc-esses, Edited by J. I. Steinfeld. Plenum Press, New V--t. 1001

York, 1981. ²⁸A.K. Knudsen, "Process for the Preparation of Submicron-Sized Titanium Diboride Powders,"

 Vis. Pat. Appl. No. 755393 (1985); Chem. Abstr., 106:89225e (1987).
 ²⁹J. J. Ritter, "A Low-Temperature Chemical Process for Precursors to Boride and Carbide Ceramic Powess for Precursors to Boride and Carbide Ceramic Pow-ders"; pp. 21-31 in Ceramic Powder Science, Advances in Ceramics, Vol. 21. Edited by G. L. Messing, K. S. Mazdiyasni, J. W. McCauley, and R. A. Haber. The American Ceramic Society, Westerville, OH, 1987. ³⁰F. A. Cotton and G. Wilkinson; p. 824 in Ad-vanced Inorganic Chemistry, 4th ed. Wiley, New York, 1980

1980

J. Am. Ceram. Soc., 71 [4] C-183-C-184 (1988)

High-Temperature Behavior of Chemically Treated Silicon Nitride Powders

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The mechanical properties of chemically treated, then sintered, Si_3N_4 was studied. Raw materials consisted of two types of Si_3N_4 produced by the nitridation of silicon. The chemical treatment involved leaching in different acids (HCl, HNO₃, HF, and combinations thereof). The powders were sintered by hot isostatic pressing with 2.5% yttria, and the high-temperature properties of the resultant materials were evaluated by the stepped-temperature stress rupture (STSR) method (24-h hold time at 150-MPa stress at 1000°, 1100°, 1200°, 1300°, and 1400°C). A significant decrease in high-temperature performance was observed for acidleached powders, especially when HF-containing acids were used.

THE successful application of advanced structural ceramics presupposes precise knowledge of the relations between the chemical and physical attributes of the presintered materials (ceramic powders+ powder systems), forming processes, etc., and the relevant material properties. Also, the relations between the material properties and performance of the final component in its particular environment/ application are obviously required to be thoroughly understood if technical success is to be guaranteed.

Alternative routes for the synthesis of Si₃N₄ powders include the conventional nitridation of silicon, decomposition of

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metallorganic precursors (CVD and laserdriven reactions), the imide process, and the carbothermic reduction of silica in nitrogen. The various methods yield Si₃N₄ powders with specific characteristics that must be considered during subsequent forming and sintering. These powder characteristics can also profoundly influence material properties.

In the present work, attention was focused on alternative acid-leaching treatment of Si₃N₄ powders produced by nitriding silicon powders. Acid leaching is often used to eliminate undesirable contaminants and/or remaining elemental silicon in the "raw nitride" that may adversely affect subsequent material properties.¹ The leaching treatment may also affect the sinterability of the nitride itself by modification of morphology, surface chemistry, and/or the chemical composition of the glass phase in the sintered component.

Basically, in the conventional nitridation of elemental Si, two routes can be used. Impure silicon is partially or totally nitrided and the resultant raw nitride purified. Alternatively, purified silicon is nitrided totally and the product reduced to a sinterable state with a minimum of contamination.

The original Si₃N₄ powders* (Siconide P95) were produced by nitriding pure silicon powder (Sicomill IV D)* according to standard procedure for production, including computer-governed reaction control. After the Si₃N₄ was nitrided, it was milled either in an iron-free environment (P95-1) or with equipment containing iron (P95-2) (Table I). The powders were leached for 6 h at 50°C with three different acids while stirring: 2M HNO₃, 1M HF+1M HNO₃, and 1M HF+ 1M HCl. After the powder was leached, it was washed thoroughly with distilled water. Leaching and washing were performed in polypropylene equipment. Drying was conducted for 24 h at 100°C in air; the resultant chemical compositions are shown in Table I.

Chemical Analyses of the Powders P95-1 and P95-2 Before and After Leaching Table I.

Element (wt%)			Leaching in			
	Untreated		HNO ₃		HNO ₃ +HF	HCI+HF
	P95-1	P95-2	P95-1	P95-2	P95-1	P95-1
Fe	0.027	0.07	0.025	0.06	0.022	0.025
Al	0.044	0.04	0.036	0.04	0.034	0.035
Ca	0.003	< 0.01	0.005	< 0.01	0.005	0.004
С	0.44	0.31	0.53	0.78	0.40	0.48
0	1.0	1.0	1.2	1.2	1.5	0.83
F	< 0.01	< 0.01	0.01	< 0.01	0.02	0.02
Cl	< 0.01	< 0.01	< 0.01	< 0.01	< 0.01	< 0.01

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